

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Akshey Seghal

Application No.: 10/620,895

Filed: July 16, 2003

For: COMPOSITIONS AND METHOD

FOR REMOVING PHOTORESIST AND/OR RESIST AT PRESSURES RANGING FROM AMBIENT TO

**SUPERCRITICAL** 

Confirmation No.: 8934

Group No.: 1746

Examiner: Bibi Sharidan Carrillo

SMALL ENTITY STATEMENT 37 CFR 1.27

353 Sacramento Street, Suite 2200 San Francisco, CA 94111 (415) 772-4900

M/S RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 **CERTIFICATE OF MAILING** 

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on May 3, 2005.

STALLMAN & POLLOCK LLP

ated: 05/3 /2005 By: Jeongia K. Stith

Sir:

Applicant is a small entity.

Respectfully submitted,

STALLMAN & POLLOCK LLP

Date: May 3, 2005

Jason/D. Lohr (Reg. No. 48,163)

Attorneys for Applicant(s)

Atty Docket No.: SCP-9410